



EV550719147

Inventor: **Brian E. Cron**

Title: **Methods for Conditioning Surfaces of Polishing Pads After Chemical Mechanical Polishing**

Assignee: **Micron Technology, Inc.**

Serial No.: **10/075,172**

Filed: **February 13, 2002 [RCE Filed Herewith]**

INFORMATION DISCLOSURE STATEMENT

PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98

The attached Form PTO-1449 is submitted in compliance with 37 CFR §1.56. Pursuant to FEDERAL REGISTER, Vol. 69, No. 182, pg. 56542 (September 21, 2004), no copies of any cited U.S. patents or U.S. published applications are included herewith. No admission is made regarding whether the listed reference is prior art.

Citation of this patent is respectfully requested.

Dated: _____

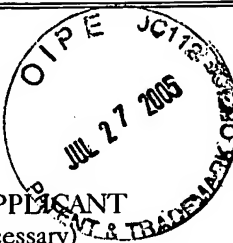
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Respectfully submitted,

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Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)ATTY. DOCKET NO.
MI22-1804SERIAL NO.
10/075,172APPLICANT
Brian E. CronFILING DATE
Feb. 13, 2002 [RCE filed herewith]GROUP
3723

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,776,691 B2	08/04	Nishimura et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Sub-class	Translation	
							Yes	No
	AK							
	AL							
	AM							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AN	
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